

SiF_3

SiF_3 (г) + Hf

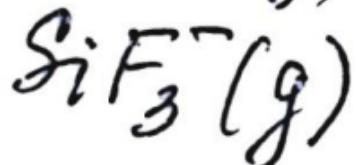
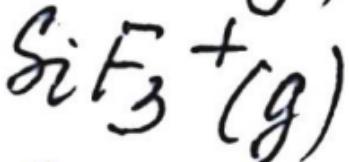
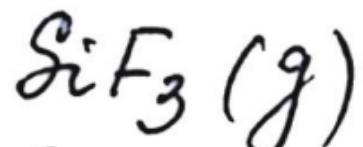
2659-IV ТКВ

Невзведен в.к.

Физико-хим. обработка SiF_3 (г), ЗС

Lommelck 9581

1972



m.g.c6.b4

Peadley J.B., Gseard B.S.
CATCH tables. Silicon
Compounds Sussex,
Univ. of Sussex, Brighton,



1972

SiF₃ BP-5049-XIV 1973

Wang J. Ling-Pai,

Margrave J.L. Franklin J.L.

"J. Chem. Phys.", 1973, 58, HE2, 5417-5421.

(A)

(cc. CF₃; II)

SiF_3^+ Rosenstock H. M. et al 1977

T. g. J. Phys. Chem. Ref. Data,
CBBA 1977, 6. Suppl. N1, p 1-385

$\text{SiF}_3(\text{gas})$ 05/26/77 5544. 1977

Farber Jr., Srivastava
R.D.

(SHf) (Space Sciences, Inc.
Monrovia, Ca 91016)
Mass spectrometric determination of the heats of formation of the silicon fluorides

~ preprint part, ut maren

reprint number N 11

6422 n 25217

$\text{SiF}_3(\text{g})$

AFH

On 37144

1978

$\Delta_0(\text{F}_3\text{Si}-\text{H})$

Doncaster A.M., Walsh R.

J. Chem. Kinetics, 1978, 10, 101-110

Kinetics of the Gas-Phase Reaction
Between Iodine and Trifluorosilane
and the Bond Dissociation Energy
 $\Delta(\text{F}_3\text{Si}-\text{H})$.

ommited 6422 1978

$\text{SiF}_3(2)$

Farber M. et al.

J. chem. Soc. Faraday Trans I, 1972,
~~Heg at al. No.~~ 25, 40.

ABER, 1089 - 1095

Mass spectrometric determination
of the heats of formation
of SiF , SiF_2 , SiF_3

SiF_3

Farber M.

1979

Gov. Rep. Announc
(AII) Index (U.S.), 1979, 79 (20)
98

•
(ent. Bad; III)

SiF_3

1981

Walsh Robin.

Accounts Chem. Res.,

ΔH_f

1981, 14, N8, 246 - 252.



(cu. $\text{Si}_2 \text{H}_5$; ?)

$\text{SiF}_3(2)$ Om. 2/314 1982

McMillen D.F., Golden D.H.,

$\Delta_f H^\circ$; Ann. Rev. Phys. Chem. 1982,
33: 493-532.

SiF₃(z)

lom. 17739/

1983

Walsh R.,

J. Chem. Soc. Faraday

Trans., 1983, Pt 1, 79, N 9,

2233-2248.

1540;

$\text{SiF}_3(2)$

(Om. 21486)

1984

Schlegel H.B.,

J. Phys. Chem., 1984, 88,
N^o25, 6254-6258.

Kb. hex. phases

$\text{SiF}_3(2)$ Селезнёв В. В., Соско-
стюник В. Г.,

1986

Исследование структуры и
энергетики молекул.

Межвузовский сборник научных
трудов Ивановского химико-
технологического института,
Иваново, 1986,

144;

26-27. (есть в карточке) 26-27.

SiF_3

(OM. 29910)

1988

Weber M.E., Armentro-
ut P.B.,

ΔH_f^0 ,
 g ,

J. Chem. Phys., 1988,
88, VII, 6898-6910.

Energetics and dynamics

in the reaction of Li^+ with
 LiF_x . Thermochemistry of
 LiF_x and LiF_x^+ ($x=1, 2, 3$)

SiF_3^+

1989

$(\Delta f H_{298}^0)$

110: 199454u Reactions of argon(1+), neon(1+), and helium(1+) with tetrafluorosilane from thermal energy to 50 eV c.m. Weber, M. E.; Armentrout, P. B. (Dep. Chem., Univ. California, Berkeley, CA 94720 USA). *J. Chem. Phys.* 1989, 90(4), 2213-24 (Eng). Guided ion-beam techniques are used to measure the cross sections for reaction of SiF_4 with Ar^+ , Ne^+ , and He^+ from thermal to 50 eV. Charge transfer followed by loss of F atoms are the sole processes obsd. All SiF_x^+ ($x = 0-4$) products are obsd., except for SiF_4^+ from reaction with Ne^+ and He^+ , and Si^+ from reaction with Ar^+ . At high energies, the dominant products are SiF_3^+ in the Ar system, and SiF^+ in both the Ne and He systems. There is some evidence in the Ne system for an excited state of SiF_3^+ at 5.7 eV. In the Ar^+ and Ne^+ reactions, the obsd. energetics are consistent with literature thermochem., but with He^+ , reaction barriers are obsd. A value of $\Delta H_{f,298}^0(\text{SiF}_3^+) = -30.1 \pm 0.9$ kcal/mol is derived, which is in agreement with previous values but is much more precise. The obsd. product distributions and energetics are explained by consideration of the potential energy surfaces and the difference in ionization potentials of the rare gases. Finally, the relationships of these reactions to plasma deposition and etching are discussed.

C.A.1989, 110, N22

SiF_3^+

1989

23 Б4029. Реакции Ar^+ , Ne^+ и He^+ с SiF_4 от термических энергий до 50 эВ ц. м. Reactions of Ar^+ , Ne^+ , and He^+ with SiF_4 from thermal energy to 50 eV c. m. / Weber M. E., Argmentrout P. B. // J. Chem. Phys.—1989.—90, № 4.—С. 2213—2224.—Англ.

Методом скрещенных пучков исследованы р-ции $\text{Rg}^+ + \text{SiF}_4$, где $\text{Rg} = \text{Ar}$, Ne , He . Во всех случаях основным процессом является перезарядка, сопровождающаяся отщеплением атомов фтора. В случае Ar идентифицированы продукты, отвечающие образованию SiJ_x^+ ($x = 1, 2, 3, 4$) в р-циях с He и Ne . Проанализированы энергетич. соотношения в р-циях данного типа. Приведены оценки потенциальных Пв систем на полуколич. уровне. Данна оценка энталпии образования SiF_3^+ .

А. В. Немухин

Х. 1989, № 23

SiF_3 Om 34479 1990

Ignacio E.W., Schlegel H. B.

ΔH_f J. Chem. Phys. 1990. 92,
N. G. C. 5404-5416.

(Cer.  SiH; -)

SiFs

1993

Deutsch H., Cornelissen C.,
et al.,

nonrepetitive
cerebral Tat. g. Mass Spec 2001.
nonrepetitive Tat Processes 1993,
♂ 129, 143-8.

(all. CH; I)

SiF_3

SiF_3^+

measured
x-ray.

1993

Fisher E.R., Kickel B.Z.
et al.

J. Phys. Chem. 1993,
97 (39), 10204-10.

(cav. SiF_x , ?)

SiF_3^+

[Om. 37370]

1993

Kickel B.L., Fisher E.R.,
et al.,

M.X.

J. Phys. Chem., 1993, 97,
10 198 - 10203

Dissociative Charge-Transfer
Reactions of $N^+(^3P)$  , $N_2^+(^2\bar{g}^+)$,